

A novel metal-mode-filtered vertical-cavity surface-emitting laser with 8 μm oxide aperture and single mode output

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ABSTRACT

In this study, a new theoretical calculation of metal-mode-filtered vertical-cavity surface-emitting laser (MMF-VCSEL) is proposed. The optimized number of P-DBR and the metal layer thickness are used. The effects of the metal mode filtered structure on the threshold gain of different transverse modes is analyzed. The MMF-VCSEL can operate in fundamental transverse mode under 8 μm oxide aperture compared with the conventional oxide-confined VCSEL. Benefit from the large oxide aperture and small metal aperture, the current crowding effect is effectively avoided and the heat distribution inside the VCSEL is improved.

Introduction

Vertical-cavity surface-emitting lasers (VCSELs) are a unique type of semiconductor laser. Due to its advantages of small size, low threshold current, single longitudinal mode, fast modulation speed, low power consumption and easy integration [1,2], VCSELs have become one of the most important semiconductor lasers in the market at present. In gas sensing [3,4], laser printing [5], chip atomic clock [6] and other applications [7,8], VCSEL is required to operate in single transverse mode. Single longitudinal mode is an inherent characteristic of VCSELs, but its large transverse size usually causes multiple transverse modes operation [9].

In conventional oxide-confined VCSELs, the oxide aperture diameter is restricted to around 3 μm by the single-mode condition [10]. Small oxide aperture will cause carrier accumulation and large thermal resistance, which will increase the temperature in the active region and eventually lead to power saturation of VCSEL. In order to make VCSEL work in single transverse mode under large oxide aperture ($> 4 \mu\text{m}$), various alternative approaches have been developed, including photonic crystal VCSELs [11–13], Surface relief VCSELs [14,15], Zn diffusion VCSELs [16], anti-resonant reflecting optical waveguide VCSELs [17], Surface grating VCSELs [18,19].

Most of the above methods increase the optical loss difference

between fundamental mode and higher order modes by tailoring the top DBR of VCSEL, so as to realize the single mode operation under large oxide aperture. The spatial distribution and mode gain of each transverse mode do not change. In addition, because the metal aperture at the outlet of VCSEL is larger than the oxide aperture, carrier crowding effect still exists inside the device to affect the single-mode stability of VCSEL [20]. The majority of reported studies used metal hole to improve the side mode suppression ratio without considering the effect of the thickness of the metal layer [21,22].

In this paper, we present a new theoretical calculation of MMF-VCSEL. The structure of MMF-VCSEL differs from conventional oxide limited VCSELs in the optimized P-DBR number (8 pairs) and metal layer thickness (900 nm). By using a metal aperture smaller than the oxide aperture, the higher order modes in VCSEL is scattered more strongly than the fundamental mode, increasing the mode loss difference between the fundamental mode and the higher order modes. The 3 μm metal aperture and 8 μm oxide aperture effectively improves the current crowding effect, making the carrier distribution overlapped with the fundamental mode optical distribution better, further increasing the stability of the fundamental mode, and improving the heat distribution inside VCSEL.

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Device structure

The device structure diagram of MMF-VCSEL is shown in Fig. 1(a). N-DBR is composed of 34 pairs of $\text{Al}_{0.12}\text{Ga}_{0.88}\text{As}/\text{Al}_{0.9}\text{Ga}_{0.1}\text{As}$. P-DBR is composed of 8 pairs of $\text{Al}_{0.12}\text{Ga}_{0.88}\text{As}/\text{Al}_{0.9}\text{Ga}_{0.1}\text{As}$ and 7 pairs of $\text{SiO}_2/\text{Nb}_2\text{O}_5$. The active region consists of three pairs of $\text{Al}_{0.3}\text{Ga}_{0.7}\text{As}/\text{GaAs}$ as potential barriers and quantum wells. The oxide layer is realized with a 30 nm thick $\text{Al}_{0.98}\text{Ga}_{0.02}\text{As}$ layer. A part of $\text{Al}_{0.98}\text{Ga}_{0.02}\text{As}$ is transformed into amorphous $(\text{Al}_x\text{Ga}_{1-x})_2\text{O}_3$ to form oxide aperture after wet oxidation. A graphic metal layer is deposited on the surface of the $\text{Al}_{0.12}\text{Ga}_{0.88}\text{As}/\text{Al}_{0.9}\text{Ga}_{0.1}\text{As}$ layers of the P-DBR, which is used as a metal-filter layer and P electrode. The upper surface of the P-type electrode is patterned $\text{SiO}_2/\text{Nb}_2\text{O}_5$ dielectric film layers. Fig. 1(b) illustrates the relationship between material gain and reflectivity of MMF-VCSEL with respect to wavelength. The optimal alignment of both parameters is attained at the central wavelength of 850 nm.

Simulation analysis and conclusions

In order to increase the mode volume of the fundamental mode light to increase output power and reliability, an oxide aperture size of 8 μm was used in MMF-VCSEL. Using Maxwell's equations and the boundary conditions at the core-cladding interface one can find the transverse electromagnetic modes supported by the waveguide, which are characterized by their propagation constants and characteristics field distributions in the transverse plane [23]. The optical field distribution of the conventional single mode VCSEL(SM-VCSEL) and MMF-VCSEL with 8 μm oxide aperture are shown in Fig. 2, simulated by COMSOL (V 4.1). As depicted in Fig. 2(a), the P-DBR of traditional SM-VCSEL is composed of 22 pairs of $\text{Al}_{0.12}\text{Ga}_{0.88}\text{As}/\text{Al}_{0.9}\text{Ga}_{0.1}\text{As}$, the first three transverse modes LP_{01} , LP_{11} and LP_{21} are all well confined within the oxide aperture with little scattering. This indicates that in traditional SM-VCSEL, the higher-order mode and the fundamental mode are subject to almost the same mode gain and mirror loss, and therefore prone to multi-mode operation. In the MMF-VCSEL, a 3 μm metal aperture is adopted, as shown in Fig. 2(b), the metal aperture causes the high-order mode to suffer strong scattering, which leads to decreased mode gain and increased optical loss of the high-order mode, so that the MMF-VCSEL can keep the single-mode operation.

The lasing threshold condition of VCSEL can be expressed as:

$$\Gamma g_{th} = \alpha_{in} + \alpha_{mirr} \quad (1)$$

Where Γ is the optical confinement factor, Γ represents the limiting effect of waveguide structures on both sides of the active region on the light field. A higher Γ results in increased field intensity within the active region, leading to a higher probability of electron-hole recombination in that area. And the device threshold can be effectively reduced. Γ is expressed as:

$$\Gamma = \frac{\int |E|_{active}^2}{\int |E|_{device}^2} \quad (2)$$

g_{th} is the threshold material gain, and Γg_{th} is called threshold gain. The α_{in} is the intrinsic loss, and α_{mirr} is the mirror loss expressed by equation (3). It represents the light leakage loss caused by the light reflected by the DBR on both sides.

$$\alpha_{mirr} = \frac{1}{L_{eff}} \ln \frac{1}{\sqrt{R_t R_b}} \quad (3)$$

Where L_{eff} is the effective cavity length of the VCSEL, R_t and R_b denote the reflectivity of the top mirror and the bottom DBR. The reflectivity of the metal layer thickness ranging from 0 to 3 μm is shown in Fig. 3 (a). The reflectivity changes periodically with an increase of the metal thickness. The metal layer is between the periodic DBR and the dielectric film, and this periodic change is determined by the Bragg reflection condition. Within a specific thickness range, where the phase satisfies the condition, the reflectivity will stay at a high level due to constructive interference. However, when interference cancellation occurs, the reflectivity will decrease. The light absorption of the metal layer is fitted to the reflectivity formula. It can be expressed as:

$$R' = R^*(1 - \Gamma_{metal}*(1 - e^{-\alpha z})) \quad (4)$$

Where R is the reflectivity without considering the absorption of the metal layer, Γ_{metal} is the light limiting factor of the metal layer, α is the absorption coefficient of the metal and z is the thickness of the metal layer. The mode loss of different modes can be obtained by calculating the reflectance of regions with and without metal layers respectively, and then weighting them according to the proportion of light distribution in different regions. The correlation between the metal layer thickness and α_{mirr} of the MMF-VCSEL is presented in Fig. 3 (b). The α_{mirr} of LP_{01} and LP_{11} modes are both increase with the metal thickness rises. And the difference between LP_{01} and LP_{11} increases with the thickness of the metal layer. High fundamental mode loss is not desirable, so a metal layer thickness of 900 nm was eventually determined. The results in [24] can be used as a reference for modes damage. The difference in values may be due to differences in calculation methods and device structures. The mode damage difference of MMF-VCSEL can bring higher single-mode operating current compared with the conventional SM-VCSEL. It benefits to the higher single-mode output power.

Fig. 4 (a) shows the optical confinement factor difference between LP_{01} and LP_{11} modes of the MMF-VCSEL and traditional SM-VCSEL at different metal and oxide aperture diameters. For MMF-VCSEL, the oxide aperture diameter is fixed to 8 μm and the diameter of the metal aperture change from 2 μm to 8 μm . Compared with traditional SM-VCSEL, MMF-VCSEL shows a greater difference in light confinement factor, which is due to the strong scattering effect of metal aperture on the light mode in VCSEL. This scattering effect decreases with the increase of the metal aperture size. When the metal aperture size is the

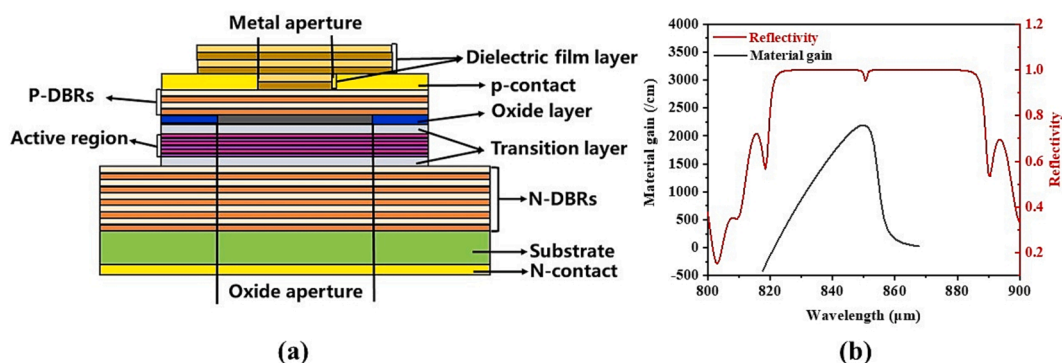


Fig. 1. (a) Structure diagram of MMF-VCSEL. (b) Material gain and reflectivity vary along wavelength.

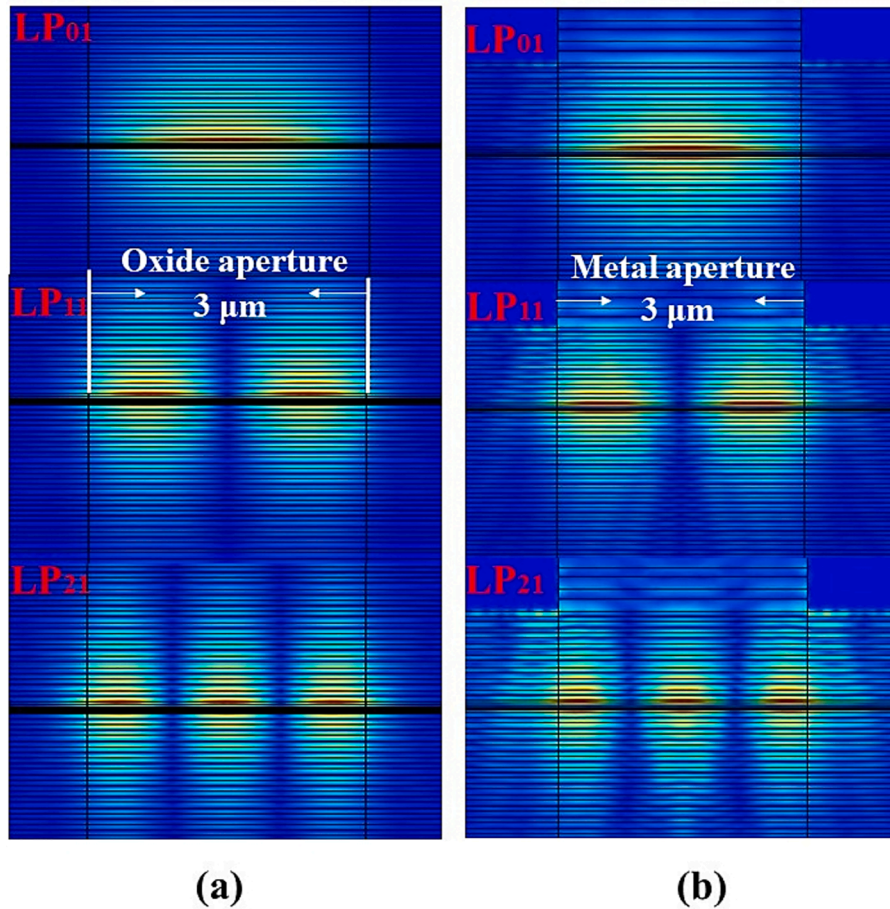


Fig. 2. Optical field distribution inside cavities of (a) the conventional SM-VCSEL and (b) MMF-VCSEL.

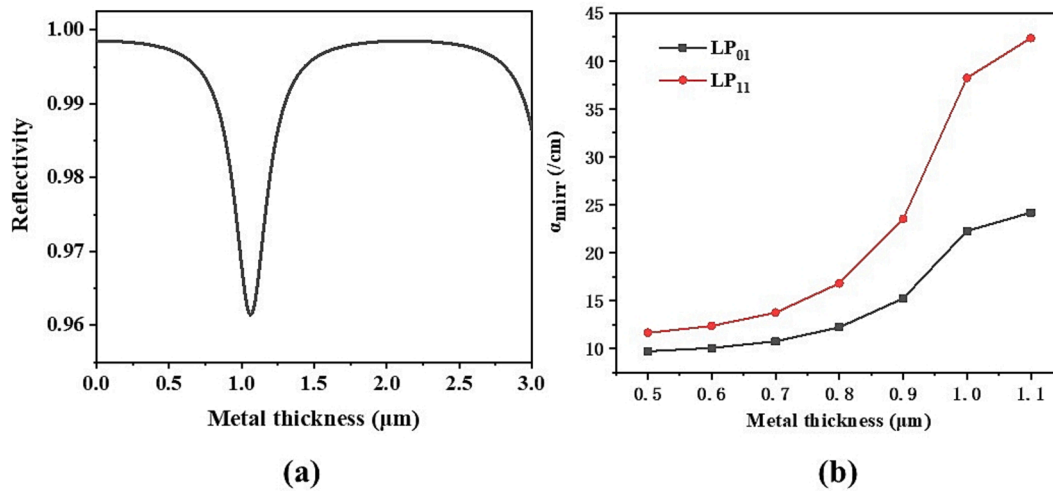


Fig. 3. (a) Reflectivity of the top mirror varies with the metal thickness. (b) Modes LP₀₁ and LP₁₁ losses of MMF-VCSEL vary along the metal thickness with 3 μm metal aperture.

same as the oxide aperture size, the metal aperture loses its modulating effect on the transverse mode of VCSEL. The mode loss difference between the LP₀₁ and LP₁₁ modes for both the MMF-VCSEL and conventional SM-VCSEL as a function of aperture size is shown in Fig. 4(b). Because the higher order modes are more distributed in the metal layer with low reflectance, MMF-VCSEL has a larger loss difference between the fundamental mode and the higher order mode. Due to the weakening

of the scattering effect of the metal aperture, the mode loss difference also decreases with the increase of the metal aperture diameter. The above results show that compared with traditional SM-VCSEL, MMF-VCSEL has stronger scattering effect on transverse optical mode, and makes the fundamental mode have larger optical mode gain and lower optical loss than the high order modes. Therefore, MMF-VCSEL can realize more stable fundamental mode operation.

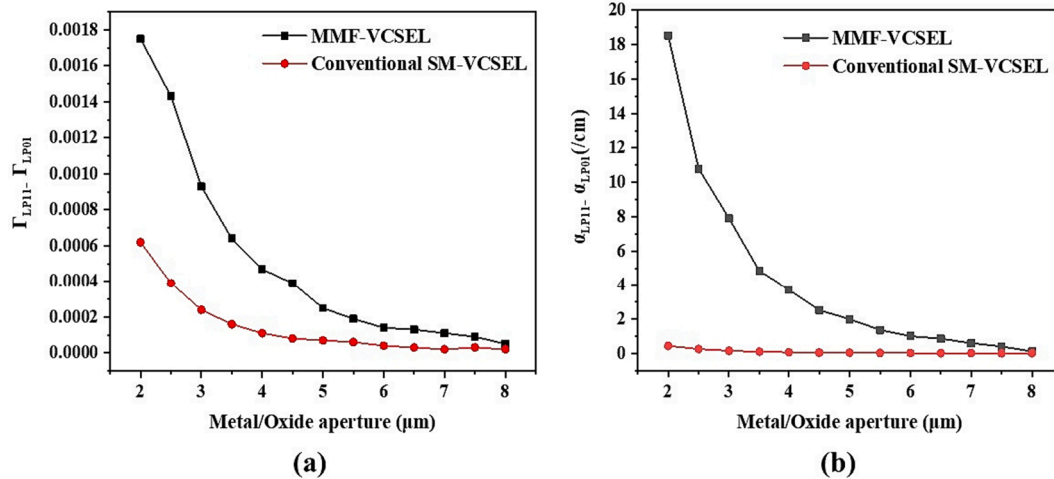


Fig. 4. (a) Optical confinement factor difference and (b) Difference of mode losses of LP₀₁ and LP₁₁ between MMF-VCSEL and conventional SM-VCSEL along metal/oxide aperture.

Due to the combination of a larger metal contact ring with a smaller oxide aperture, there is a current crowding effect exists in traditional SM-VCSEL [25], which shows a stronger injection close to the oxide aperture rim than in the center. This uneven current distribution will lead to the spatial hole burning effect and ultimately affect the mode stability of VCSEL [26]. The current crowding effect is greatly improved in the novel MMF-VCSEL design, which benefits from the smaller metal contact ring and larger oxide aperture, since the current tends always to follow the shortest path between the two electrodes [25]. When the metal aperture is larger than oxide aperture, the shortest path passes through the edge of the oxidation hole, resulting in the current crowding effect. At the large oxide aperture and small metal aperture, the shortest path is closer to the oxidation hole center, and the current crowding effect is also improved. The active region heat model based on carrier injection heat production mechanism was established based on finite element method [27–29]. SM-VCSEL and MMF-VCSEL device model are established by COMSOL (V 4.1), and the active region temperature variation and current density distribution were simulated.

Fig. 5 displays one-dimensional distribution of normalized current density in the active regions of the MMF-VCSEL and conventional VCSELs with 3 μm and 8 μm oxide aperture. The conventional VCSELs

has 10 μm metal aperture, and the MMF-VCSEL has 8 μm oxide aperture and 3 μm metal aperture. Due to the carrier crowding effect, the traditional VCSELs present a cat’s ear shaped current distribution along the transverse direction. At the same oxide aperture of 8 μm, MMF-VCSEL has a more uniform current density distribution than traditional oxide limited VCSEL. It shows that the presence of metal layer does have a positive effect on the current density distribution of MMF-VCSEL.

Due to the high resistance and thermal resistance caused by small oxide aperture, conventional SM-VCSEL is prone to thermal rollover, and the operating current of is generally below 5 mA [30]. Benefits from the large oxide aperture and small metal aperture, MMF-VCSEL is promising for single-mode operation at larger current with lower device temperature. Fig. 6 depicts the one-dimensional distribution of active region temperature for MMF-VCSEL and conventional SM-VCSEL at varying injection currents. Even at higher operating currents, the MMF-VCSEL still has lower device temperatures than the traditional SM-VCSEL. Although large oxide aperture can lead to an increase in device threshold current, the greater thermoelectric performance makes it possible for MMF-VCSEL to achieve stable single-mode output with high power.

Conclusion

In this study, a novel MMF-VCSEL design that can achieve single-mode output at a large oxide aperture is presented. The simulation results show that MMF-VCSEL realizes the transverse mode control in VCSEL through the strong light scattering effect of metal aperture, which is different from the mode control method achieved by oxide aperture in the existing reports. Benefit from the 8 μm oxide aperture and 3 μm metal aperture of MMF-VCSEL, the current crowding effect is improved, and the device has better electro-thermal performance. It is possible for MMF-VCSEL to maintain stable high-power single-mode operation at higher current.

CRedit authorship contribution statement

Jingfei Mu: Conceptualization, Data curation, Formal analysis, Investigation, Methodology, Software, Validation, Visualization, Writing – original draft, Writing – review & editing. **Yinli Zhou:** Conceptualization, Formal analysis, Funding acquisition, Methodology, Project administration, Resources, Software, Supervision, Validation. **Xing Zhang:** Project administration, Resources. **Jianwei Zhang:** Funding acquisition, Project administration. **Chao Chen:** Resources. **Zhuo Zhang:** Formal analysis. **Tianjiao Liu:** Data curation,

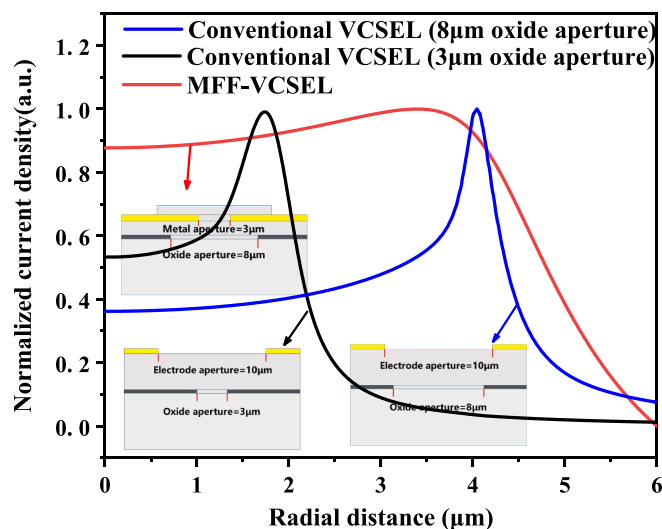


Fig. 5. Normalized current density distribution in the active regions of the MMF-VCSEL and conventional SM-VCSEL with 3 μm and 8 μm oxide aperture.

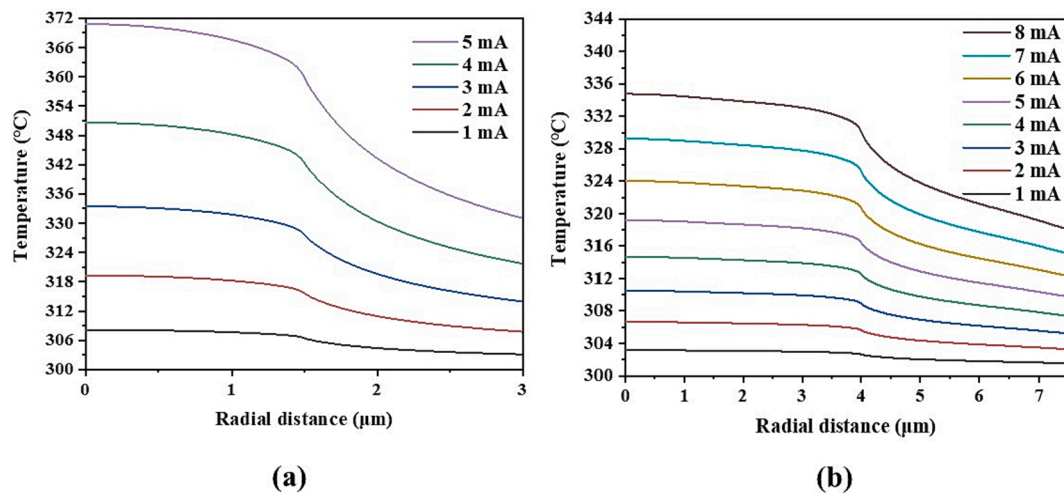


Fig. 6. Temperature distribution of the active region along injection current for (a) traditional SM-VCSEL and (b) MMF-VCSEL.

Investigation. **Yuqi Xia**: Formal analysis, Investigation. **Yuehui Xu**: Data curation. **Jingjing Sun**: Investigation. **Haopeng Bai**: Investigation. **Yongqiang Ning**: Resources. **Lijun Wang**: Resources.

Declaration of Competing Interest

The authors declare that they have no known competing financial interests or personal relationships that could have appeared to influence the work reported in this paper.

Data availability

Data will be made available on request.

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